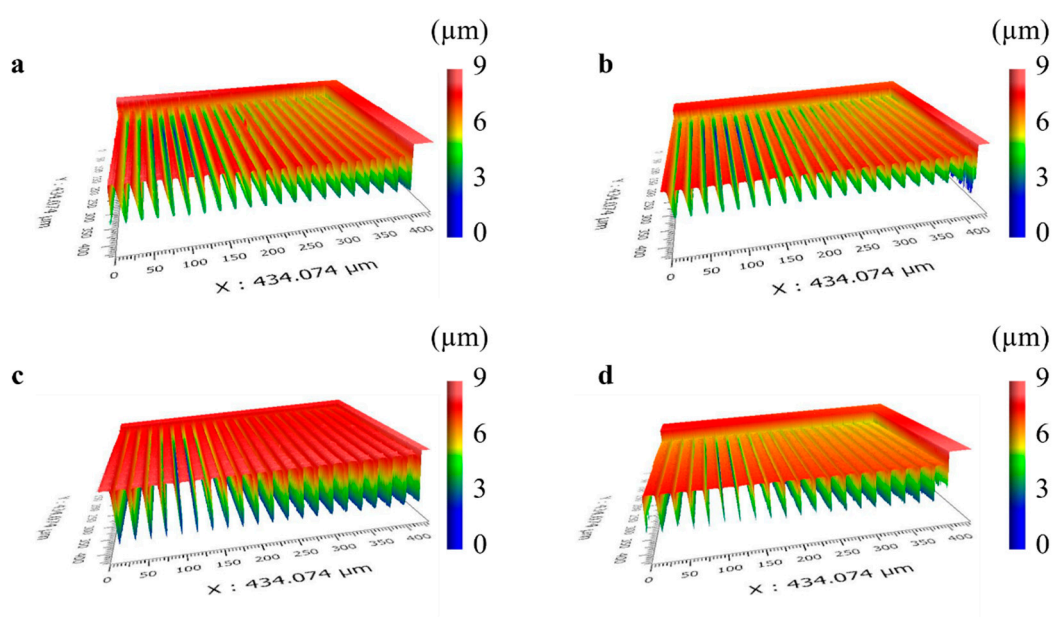


Supplementary

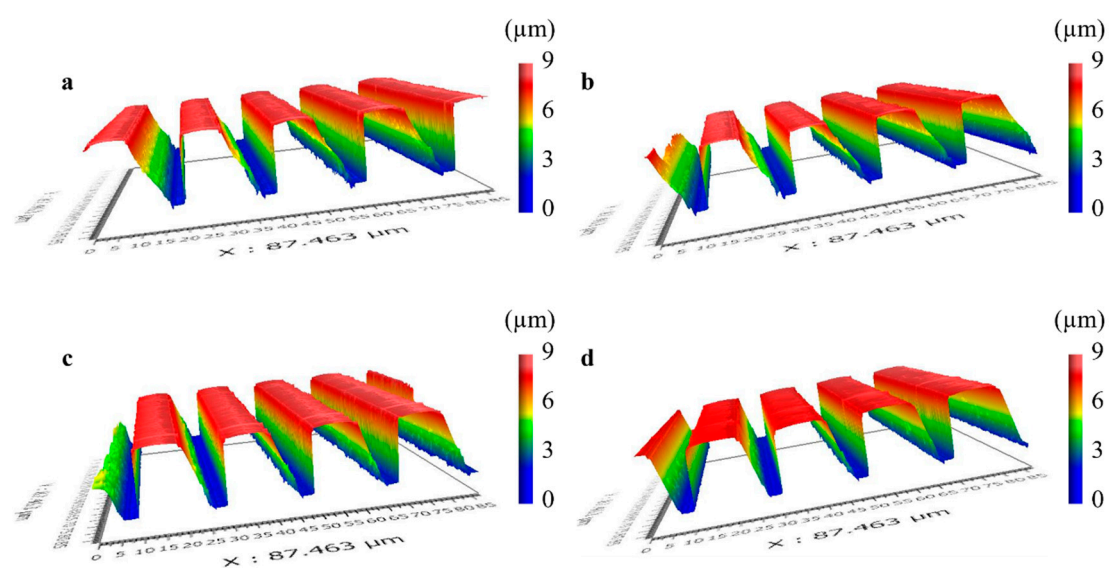
# A Reflectivity Enhanced 3D Optical Storage Nanostructure Application Based on Direct Laser Writing Lithography

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Sample images with different slope angle fabricated by the laser direct writing device



**Figure S1.** Image of 3D lithographic structure taken with 3D optical profilometer. **a** Sample with 60° slope angle structure, **b** Sample with 62.5° slope angle structure, **c** Sample with 65° slope angle structure, **d** Sample with 67.5° slope angle structure.



**Figure S2.** Image of 3D lithographic structure taken with 3D optical profilometer. **a** Sample with 60° slope angle structure, **b** Sample with 62.5° slope angle structure, **c** Sample with 65° slope angle structure, **d** Sample with 67.5° slope angle structure.